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Vishnu K. Agarwal et alFILING DATE
January 15, 2002GROUP
2813

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
VK	AA	6,204,070	03/2001	Kim			
	AB	6,207,487	03/2001	Kim et al			
	AC	6,391,803	05/2002	Kim et al			
VK	AD	6,420,230	07/2002	Derderian			
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		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
VK	AM	KR 2002002157A	01/2002	Korea				
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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Vishnu K. AgarwalPriority FILING DATE
August 31, 2000Priority GROUP
281310/050334
05/157/02

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VK	AA	6,180,481	01/2001	Deboer et al			
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Mu	AA	09/653,149		Derderian			08/31/00
Mu	AB	09/652,532		Derderian (as filed and amended 11/29/01)			08/31/00
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FOREIGN PATENT DOCUMENTS

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